

Supporting Information for

Selective thionation of naphtho[2,3-*b*]thiophene diimide: Tuning of the optoelectronic properties and packing structure

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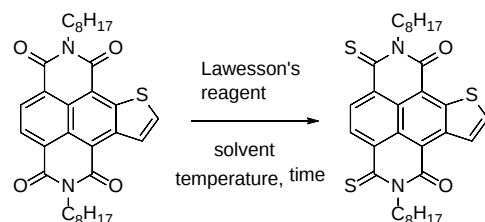
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1. Optimization of conditions in the reaction of NTI and Lawesson's reagent

Table S1. Reactions of NTI with Lawesson's reagent.



run	solvent	temperature (°C), time (h)	result	remarks
1	toluene	reflux (110 °C), 5h	no reaction	LR ^a : 4.0 eq.
2	xylene	reflux (110 °C), 5h	NTI-2S: trace	LR ^a : 4.0 eq.
3	xylene	180 °C, 5h	NTI-2S: 20%	LR ^a : 4.0 eq., Microwave irradiation in a sealed tube
4	xylene	180 °C, 2h	NTI-2S: 41%	LR ^a : 4.0 eq., Microwave irradiation in a sealed tube
5	<i>o</i> -DCB	180 °C, 2h	NTI-2S: 6%	LR ^a : 4.0 eq.
6	<i>o</i> -DCB	160 °C, 1h	NTI-2S: 45%	LR ^a : 4.0 eq.
6	<i>o</i> -DCB	160 °C, 1h	NTI-2S: 59%	LR ^a : 3.0 eq.
7	<i>o</i> -DCB	160 °C, 1h	NTI-2S: 69%	LR ^a : 2.2 eq.

^a LR: Lawesson's reagent.

2. ¹³C NMR spectrum of NTI

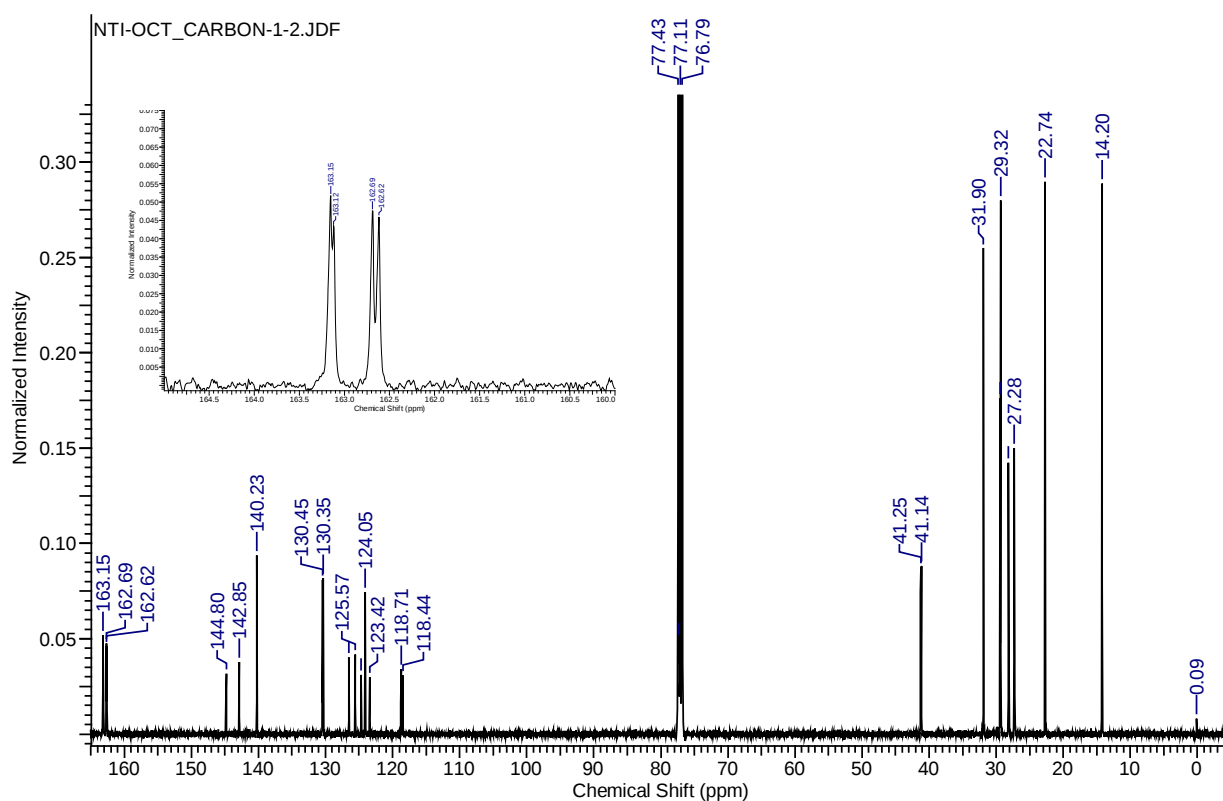


Figure S1. ^{13}C NMR spectrum of NTI.

3. Calculated electron density of NDI, NTI and NDTI^{S1}

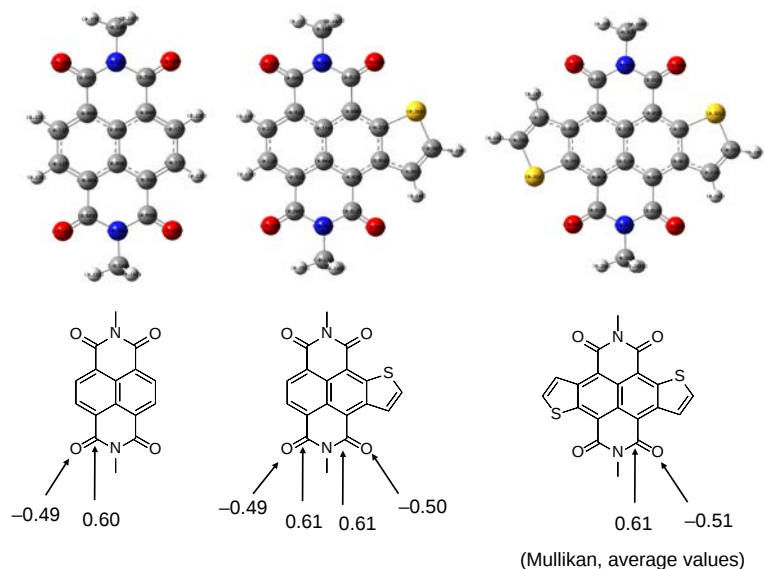


Figure S2. Calculated electron density of NDI, NTI and NDTI (DFT B3LYP 6-31g(d)).

4. Calculated structures of plausible intermediates in the reaction of NTI and Lawesson's reagent^{S2}

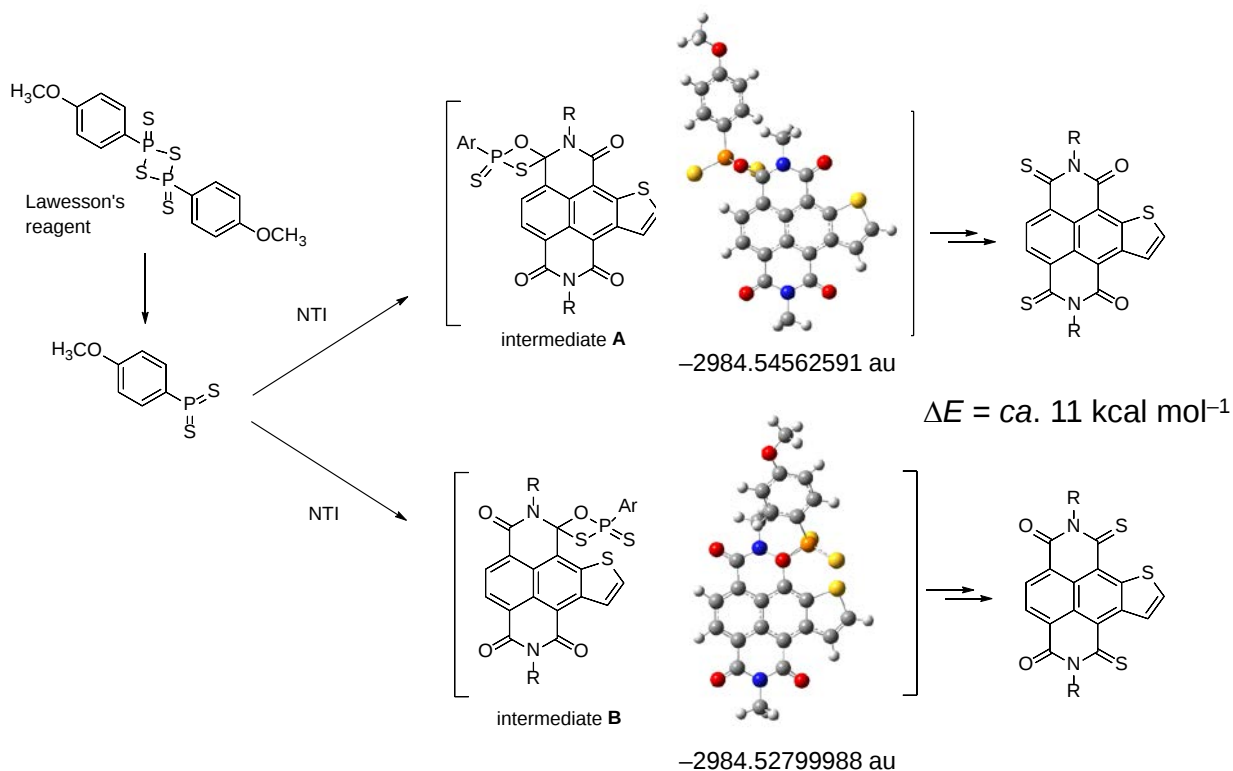


Figure S3. Plausible reaction paths of thionation and intermediates: the intermediate **A** is calculated to be energetically stable compared to the intermediate **B** by ca. 11 kcal mol⁻¹ (DFT B3LYP/6-31G(d)).

5. ^1H NMR spectra of NTI-2S under different conditions

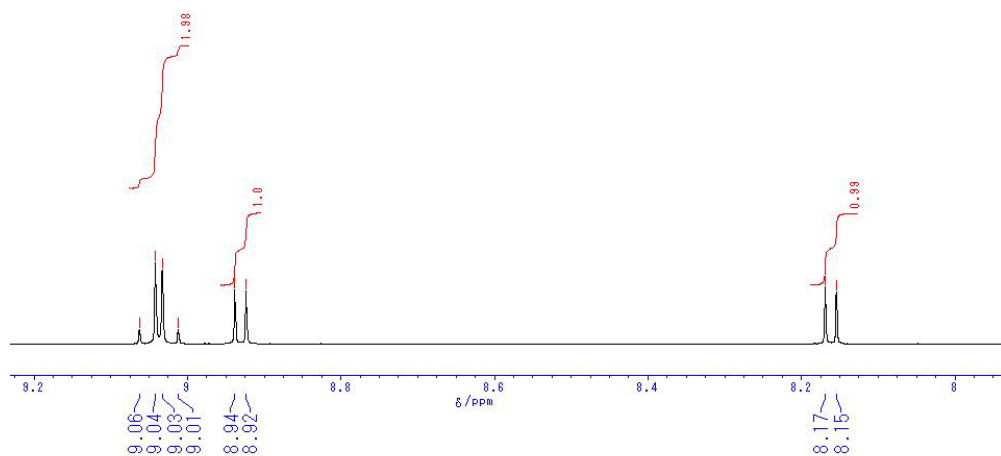


Figure S4. Pristine sample of NTI-2S.

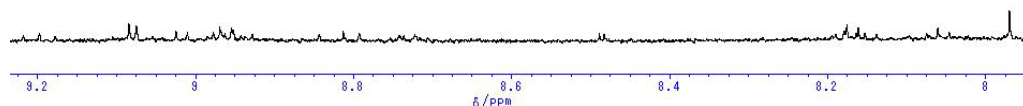


Figure S5. ^1H NMR spectra of NTI-2S under fluorescent light (room light) in air (1h).

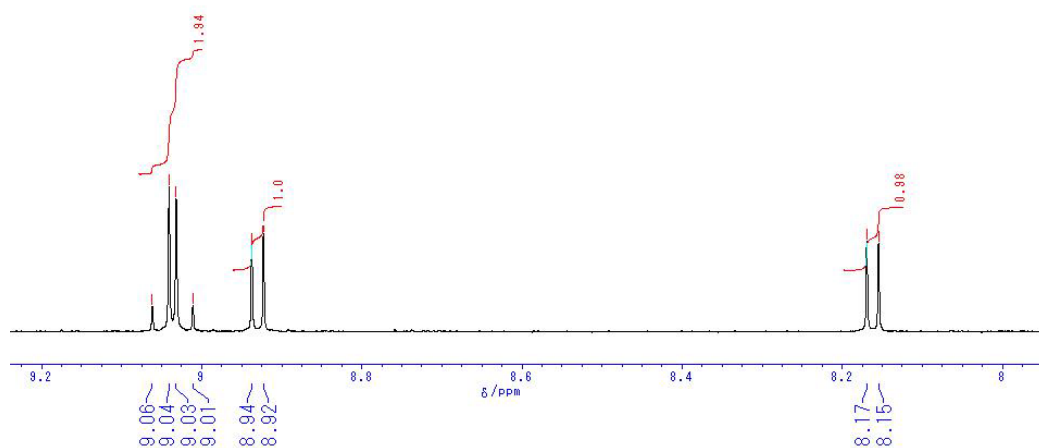


Figure S6. ^1H NMR spectra of NTI-2S under fluorescent light (room light) under argon atmosphere (1 day).

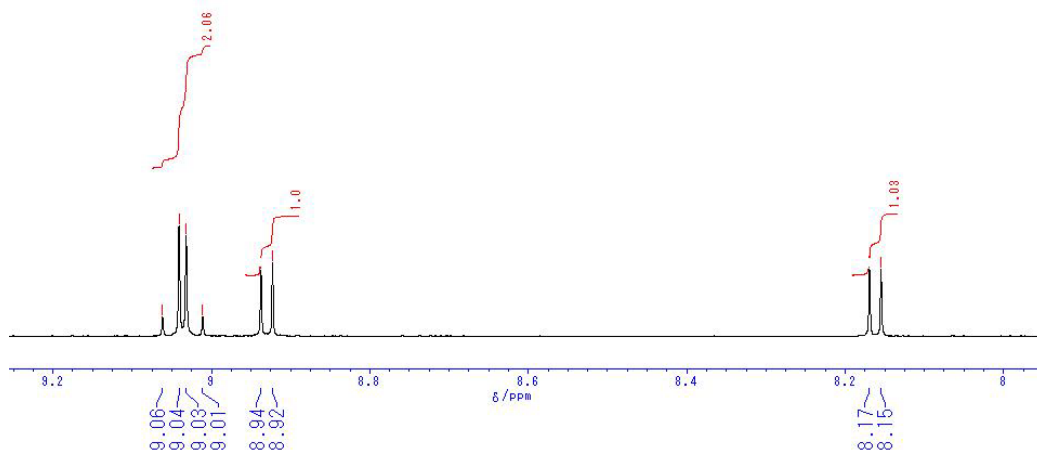


Figure S7. ^1H NMR spectra of NTI-2S in air in dark (1 day).

6. Preliminary data obtained from solution processed field-effect transistors based on NTI-2S

OFET devices based on NTI-2S were fabricated in a top-contact-bottom-gate (TCBG) configuration on a heavily doped n+-Si (100) wafer with a 200 nm thermally grown SiO_2 ($C_i = 17.3 \text{ nF cm}^{-2}$). The substrate surfaces were treated with octadecyltrichlorosilane (ODTS) as reported previously. Thin films as the active layer were spin-coated from chloroform. On top of the organic thin film, gold films (80 nm) as drain and source electrodes were deposited through a shadow mask. For a typical device, the drain-source channel length (L) and width (W) are $40 \mu\text{m}$ and 1.5 mm , respectively.

Characteristics of the OFET devices were measured at room temperature under ambient conditions with a Keithley 4200 semiconducting parameter analyzer. Field-effect mobility (μ_{FET}) was calculated in the saturation ($V_d = V_g = \pm 60$) of the I_d using the following equation,

$$I_d = C_i \mu_{\text{FET}} (W/2L) (V_g - V_{\text{th}})^2$$

where C_i is the capacitance of the SiO_2 dielectric layer, and V_g and V_{th} are the gate and threshold voltages, respectively.

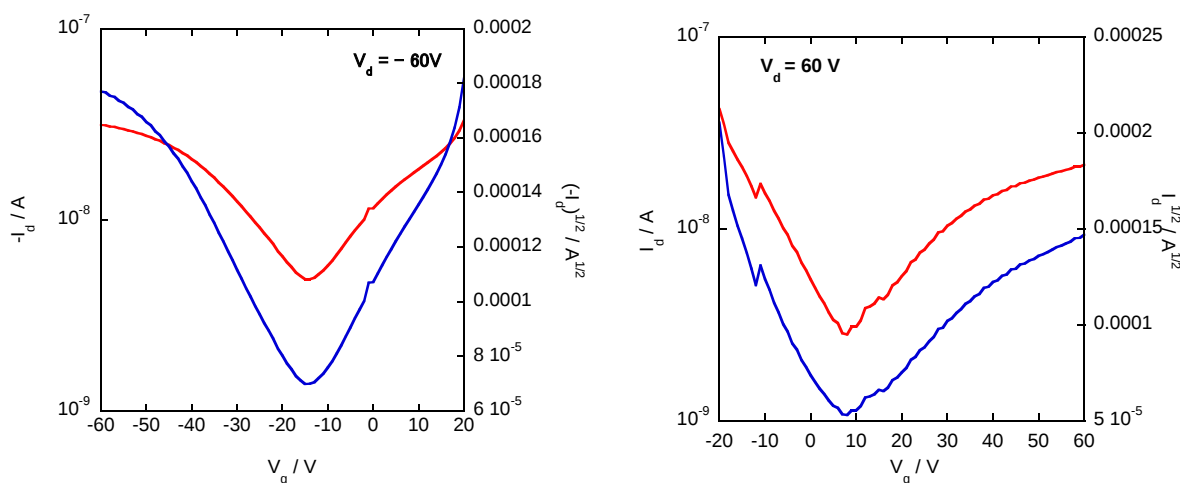


Figure S8. Transfer characteristics of NTI-2S-based transistor: p-channel operation (left) and n-channel operation (right).

7. References

- S1. Gaussian 09, Revision D.01, M. J. Frisch, G. W. Trucks, H. B. Schlegel, G. E. Scuseria, M. A. Robb, J. R. Cheeseman, G. Scalmani, V. Barone, B. Mennucci, G. A. Petersson, H. Nakatsuji, M. Caricato, X. Li, H. P. Hratchian, A. F. Izmaylov, J. Bloino, G. Zheng, J. L. Sonnenberg, M. Hada, M. Ehara, K. Toyota, R. Fukuda, J. Hasegawa, M. Ishida, T. Nakajima, Y. Honda, O. Kitao, H. Nakai, T. Vreven, J. A. Montgomery, Jr., J. E. Peralta, F. Ogliaro, M. Bearpark, J. J. Heyd, E. Brothers, K. N. Kudin, V. N. Staroverov, R. Kobayashi, J. Normand, K. Raghavachari, A. Rendell, J. C. Burant, S. S. Iyengar, J. Tomasi, M. Cossi, N. Rega, J. M. Millam, M. Klene, J. E. Knox, J. B. Cross, V. Bakken, C. Adamo, J. Jaramillo, R. Gomperts, R. E. Stratmann, O. Yazyev, A. J. Austin, R. Cammi, C. Pomelli, J. W. Ochterski, R. L. Martin, K. Morokuma, V. G. Zakrzewski, G. A. Voth, P. Salvador, J. J. Dannenberg, S. Dapprich, A. D. Daniels, Ö. Farkas, J. B. Foresman, J. V. Ortiz, J. Cioslowski, and D. J. Fox, Gaussian, Inc., Wallingford CT, 2009.
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